



# UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE  
United States Patent and Trademark Office  
Address: COMMISSIONER FOR PATENTS  
P.O. Box 1450  
Alexandria, Virginia 22313-1450  
www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/003,114	12/06/2001	Masaki Yamada	216932US2	5215
22850	7590	08/25/2004	EXAMINER	
OBLON, SPIVAK, MCCLELLAND, MAIER & NEUSTADT, P.C. 1940 DUKE STREET ALEXANDRIA, VA 22314				MANDALA, VICTOR A
		ART UNIT		PAPER NUMBER
		2826		

DATE MAILED: 08/25/2004

Please find below and/or attached an Office communication concerning this application or proceeding.

<b>Office Action Summary</b>	<b>Application No.</b>	<b>Applicant(s)</b>	
	10/003,114	YAMADA ET AL.	
	<b>Examiner</b>	<b>Art Unit</b>	
	Victor A Mandala Jr.	2826	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

#### Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

#### Status

1) Responsive to communication(s) filed on 12 August 2004.

2a) This action is **FINAL**.                                    2b) This action is non-final.

3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

#### Disposition of Claims

4) Claim(s) 1-30 is/are pending in the application.

4a) Of the above claim(s) 11-30 is/are withdrawn from consideration.

5) Claim(s) \_\_\_\_\_ is/are allowed.

6) Claim(s) 1-10 is/are rejected.

7) Claim(s) \_\_\_\_\_ is/are objected to.

8) Claim(s) \_\_\_\_\_ are subject to restriction and/or election requirement.

#### Application Papers

9) The specification is objected to by the Examiner.

10) The drawing(s) filed on \_\_\_\_\_ is/are: a) accepted or b) objected to by the Examiner.  
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).  
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).

11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

#### Priority under 35 U.S.C. § 119

12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).

a) All    b) Some \* c) None of:

1. Certified copies of the priority documents have been received.
2. Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.
3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

\* See the attached detailed Office action for a list of the certified copies not received.

#### Attachment(s)

1) Notice of References Cited (PTO-892)

2) Notice of Draftsperson's Patent Drawing Review (PTO-948)

3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)  
Paper No(s)/Mail Date \_\_\_\_\_.

4) Interview Summary (PTO-413)  
Paper No(s)/Mail Date. \_\_\_\_\_.

5) Notice of Informal Patent Application (PTO-152)

6) Other: \_\_\_\_\_.

## **DETAILED ACTION**

### **Response to Request for Reconsideration**

1. The Applicant argues against the prior art of record in the final rejection. The examiner has considered the Applicant's arguments and finds them to be persuasive and the final rejection will be retracted. Claims 1-10 will be further examined.

#### ***Claim Rejections - 35 USC § 102***

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

Claims 1-8 and 10 are rejected under 35 U.S.C. 102(e) as being anticipated by U.S.

Patent Application Publication No. 2003/0205815 Chung.

2. Referring to claim 1, a semiconductor device comprising: a first interlayer insulating layer, (Figure 4H organic low-k dielectric lower layer); a trench, (Figure 4H the are where it is labeled metal), formed in the first interlayer insulating layer, (Figure 4H organic low-k dielectric lower layer); a conductive layer buried in the trench, (Figure 4H the are where it is labeled metal), the conductive layer, (Figure 4H the are where it is labeled metal), having a surface thereof higher than a highest surface of the first interlayer insulating layer, (Figure 4H organic low-k dielectric lower layer), surrounding and adjoining the trench, (Figure 4H the are where it is labeled metal); an insulating film, (Figure 4H inorganic low-k dielectric middle layer), having a

flat surface and covering the first interlayer insulating layer, (Figure 4H organic low-k dielectric lower layer), and the conductive layer, (Figure 4H the are where it is labeled metal); and a second interlayer insulating layer, (Figure 4H inorganic low-k dielectric upper layer), formed on the insulating film, (Figure 4H organic low-k dielectric middle layer), the second interlayer insulating layer, (Figure 4H inorganic low-k dielectric upper layer), having a high etching selective ratio, (Paragraph 0090 Lines 28-30 & 34-35 and Paragraph 0106 Lines 16-20), to the insulating film, (Figure 4H organic low-k dielectric middle layer).

3. Referring to claim 2, a semiconductor device, wherein a film thickness of the insulating film, (Figure 4H organic low-k dielectric middle layer), on the first interlayer insulating layer, (Figure 4H inorganic low-k dielectric lower layer), is greater than that on the conductive layer, (Figure 4H the are where it is labeled metal).

4. Referring to claim 3, a semiconductor device, wherein the insulating film is made of a coating type material, (Paragraph 0100).

5. Referring to claim 4, a semiconductor device, wherein the insulating film, (Figure 4H inorganic low-k dielectric middle layer & Paragraph 0093-0094), has an effect of preventing diffusion of a conductor material in the conductive layer, (Paragraph 0104 Lines 52-59).

6. Referring to claim 5, a semiconductor device, wherein at least any one of the first interlayer insulating layer, (Figure 4H organic low-k dielectric lower layer), and the second interlayer insulating layer, (Figure 4H organic low-k dielectric upper layer), is made of an insulating material having a relative dielectric constant lower than that of an  $\text{SiO}_2$  film, (Paragraphs 0093-0094).

7. Referring to claim 6, a semiconductor device, wherein the insulating film, (Figure 4H inorganic low-k dielectric middle layer), is made of an insulating material having a relative dielectric constant lower than that of an SiO<sub>2</sub> film, (Paragraph 0092).
8. Referring to claim 7, a semiconductor device, wherein the conductive layer includes a barrier metal layer, (Paragraph 0104 Lines 52-59).
9. Referring to claim 8, a semiconductor device, wherein the conductive layer includes a Cu wiring layer, (Paragraph 0104 Lines 61-63).
10. Referring to claim 10, a semiconductor device, wherein the insulating layer: film is made of any one of polyarylene and berlzo cyclo-butene, (Paragraph 0092 Line 17).

***Claim Rejections - 35 USC § 103***

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

Claim 9 is rejected under 35 U.S.C. 103(a) as being unpatentable over U.S. Patent Application Publication No. 2003/0205815 Chung. In view of U.S. Patent No. 6,333,232 Kunikiyo

11. Referring to claim 9, a semiconductor device, wherein at least any one of the first interlayer insulating layer, (Figure 4H organic low-k dielectric lower layer), and the second interlayer insulating layer, (Figure 4H organic low-k dielectric upper layer), is made of

methylpolysiloxane, (Chung Paragraph 0094 where it is taught a similar dielectric is used such as hydrogenmethylsiloxane).

Chung discloses the claimed invention except for the organic dielectric material being made out of methylpolysiloxane, but Kunikiyo does in Col. 26 Lines 6-13. It would have been obvious to one having ordinary skill in the art at the time the invention was made to the low dielectric organic layer out of methylpolysiloxane, which also holds the properties of being a low k dielectric, since it has been held to be within the general skill of a worker in the art to select a known material on the basis of its suitability for the intended use as a matter of obvious design choice. In re Leshin, 125 USPQ 416.

*Conclusion*

  
NATHAN J. FLYNN  
SUPERVISORY PATENT EXAMINER  
COMMUNICATIONS FROM THE  
TECHNOLOGY CENTER 2800

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Victor A Mandala Jr. whose telephone number is (571) 272-1918.

The examiner can normally be reached on Monday through Thursday from 8am till 6pm..

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nathan J Flynn can be reached on (571) 272-1915. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Application/Control Number: 10/003,114  
Art Unit: 2826

Page 6